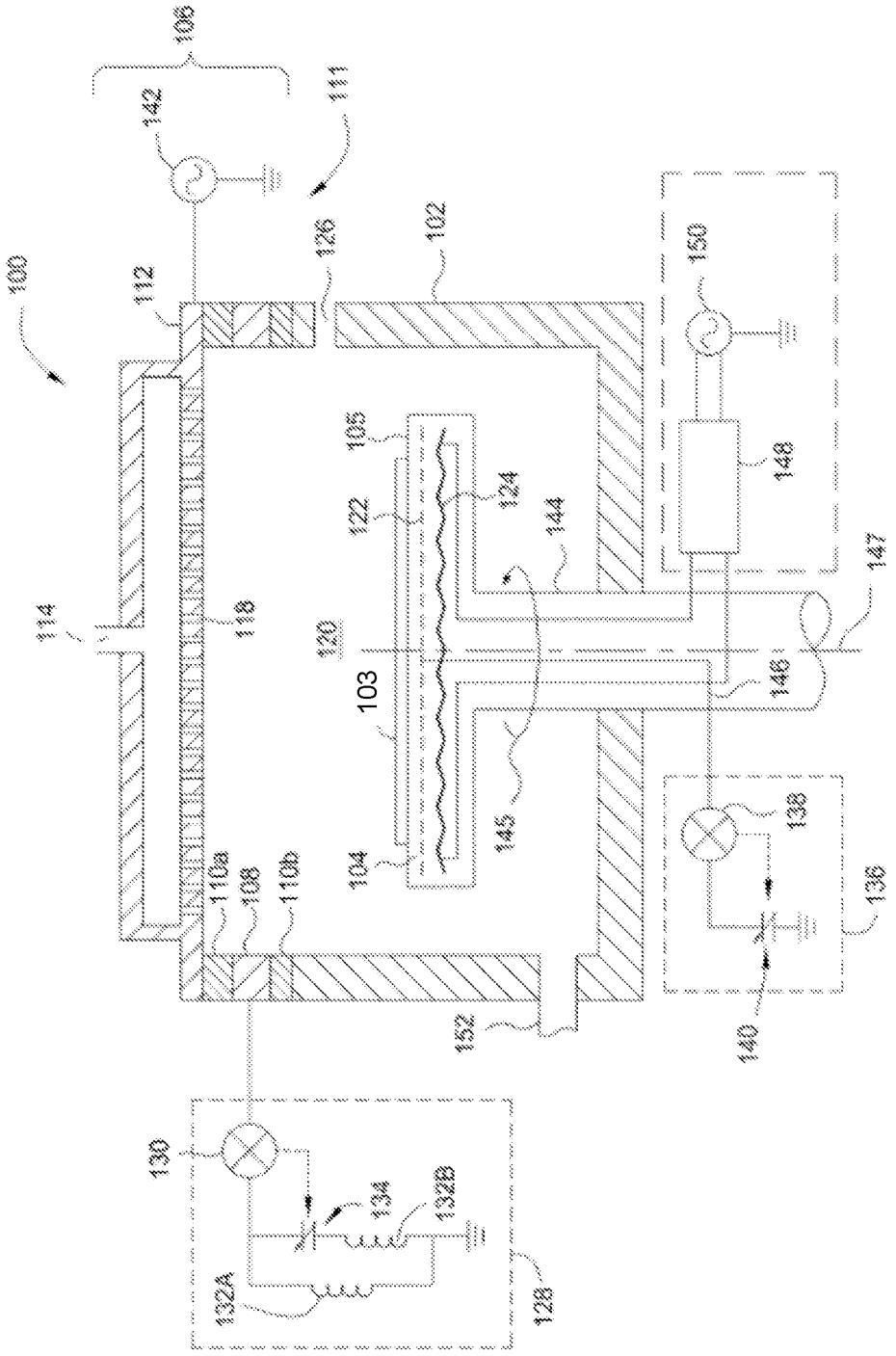

100
102
103
104
105
106
108
110a
110b
111
112
114
116
120
122
123
124
126
128
130
132A
132B
134
136
138
140
142
144
145
146
147
148
150
152

FIG. 1

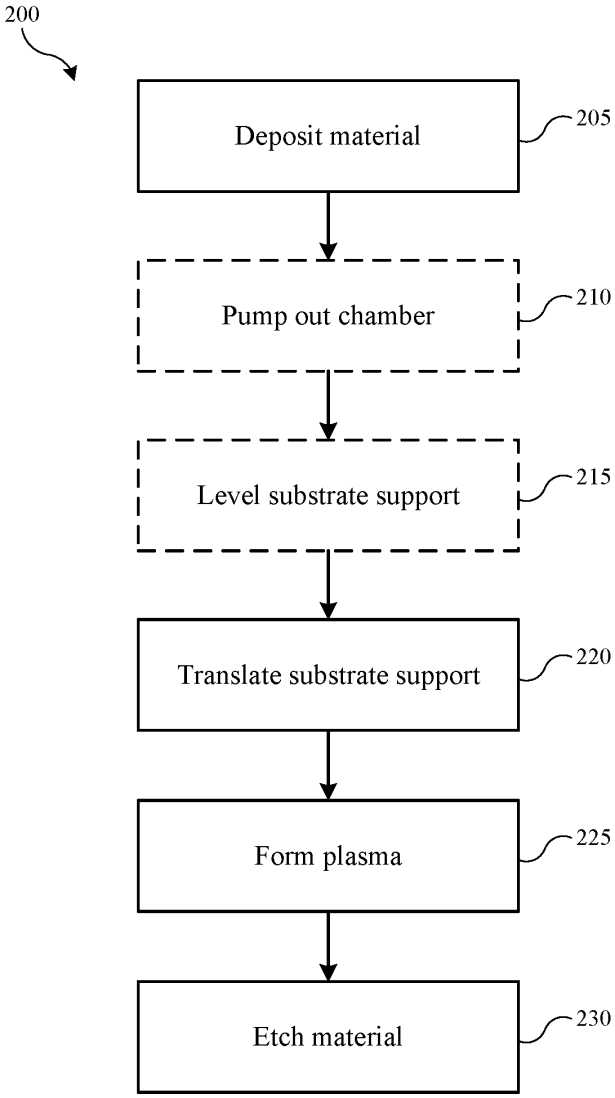

200
Deposit material
205
Pump out chamber
210
Level substrate support
215
Translate substrate support
220
Form plasma
225
Etch material
230

FIG. 2

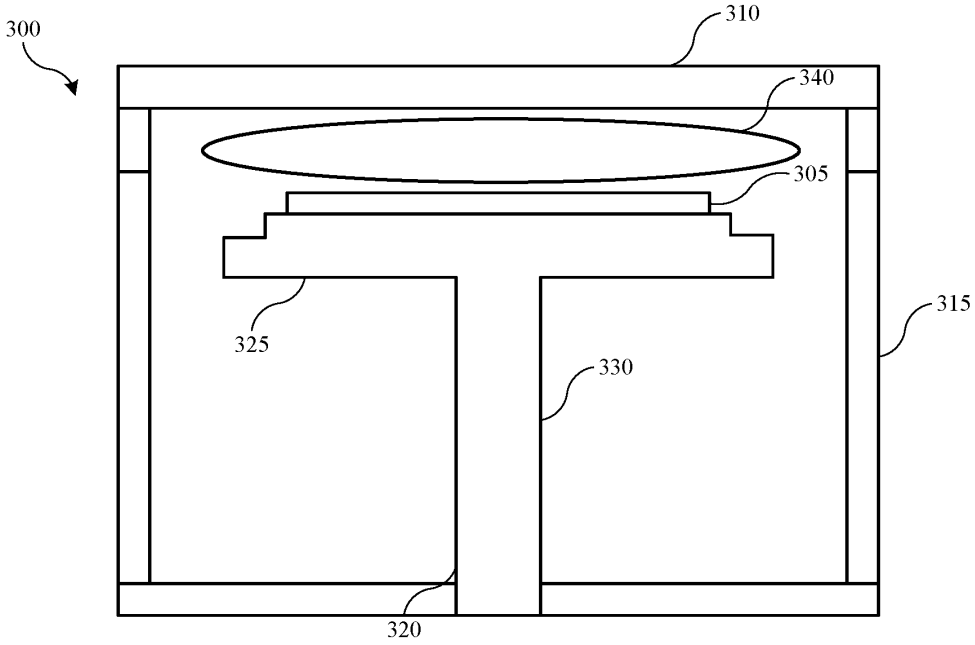


FIG. 3A

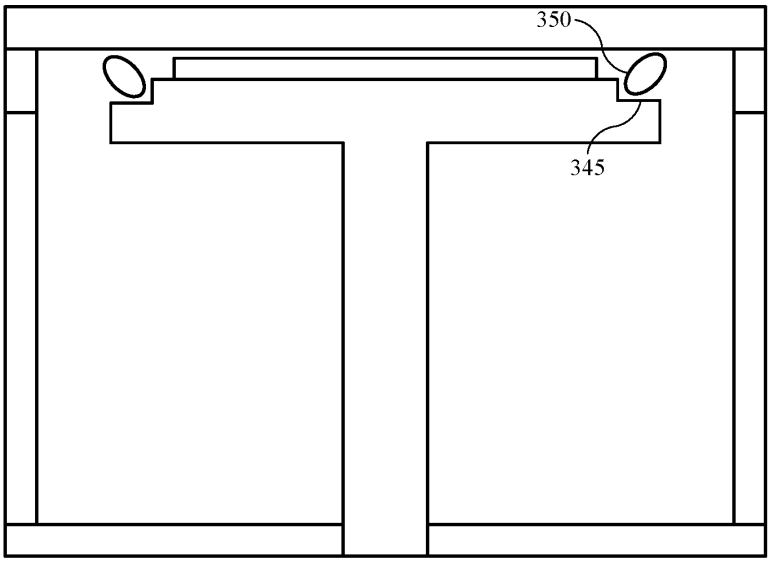


FIG. 3B

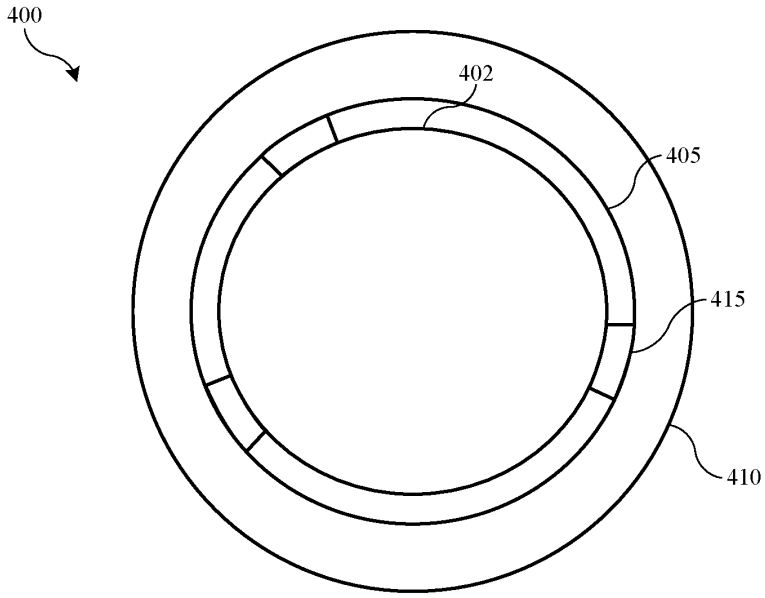


FIG. 4